



THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Yee-Chung Fu

Assignee: Advanced Nano Systems, Inc.

Amended Title: MEMS Scanning Mirror with Trenched Surface and Tapered Comb Teeth for Reducing Inertia and Deformation

Serial No.: 10/779,952 Filing Date: February 13, 2004

Examiner: Allan R. Wilson Group Art Unit: 2815

Docket No.: ANS-P105

San Jose, California
November 28, 2005

Mail Stop Amendment
COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, Virginia 22313-1450

AMENDMENT

Dear Sir:

In response to the August 18, 2005 Notice of Drawing Inconsistency with Specification, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Remarks begin on page 3 of this paper.